



BOX AF
RESPONSE UNDER 37 CFR 1.116
Expedited Handling Procedure
AU 1763
PATENT
2342-111P

IN THE U.S. PATENT AND TRADEMARK OFFICE

APPLICANT: Kazuyuki TOYODA et al.

APPL. NO.: 08/905,971 GROUP: 1763 *#15101*

FILED: August 5, 1997 EXAMINER: R. Zervigon *7/5/01*

FOR: SUBSTRATE PROCESSING APPARATUS *MW*

AMENDMENT UNDER 37 C.F.R. §1.116

Assistant Commissioner for Patents
Washington, D.C. 20231

June 29, 2001

Sir:

In reply to the Office Action dated January 17, 2001, the period for response having been extended for three (3) months to July 17, 2001, the following remarks are respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please amend the claims as follows:

34. (Amended) A substrate processing apparatus as recited in claim 1, wherein
D1 the apparatus is configured to transfer a plurality of substrate at a time and to process a plurality of substrate at a time.

Please add the following new claims:

- 35. A substrate processing apparatus as recited in claim 1, further including a plurality

07/02/2001 MA00R1 00000082 08905971

01 FC:103
02 FC:117

36.00 OP
890.00 OP

RECEIVED
JUL - 3 2001
TC 1700 MAIL ROOM